FORM PTO 1449 (*modified*)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

LIST OF REFERENCES CITED BY APPLICANT(S)
(*Use several sheets if necessary*)

Date Submitted to PTO: [DATE]

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OCT 19 2004
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ATTY DOCKET NO.	APPLICATION NO.
03500.014384.1	10/775,181
APPLICANT	
MASAFUMI KYOGAKU ET AL.	
FILING DATE	**GROUP**
FEBRUARY 11, 2004	2818

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
JW		HO9-35620	2/97	Japan			Abstract

OTHER DOCUMENT(S) (*Including Author, Title, Date, Pertinent Pages, Etc.*)

JW		Fukano, Y., et al., ***Scanning Force/Tunneling Microscopy as a Novel Technique for the Study of nanometer-Scale Dielectric Breakdown of Silicon Oxide Layer***, Jpn. J. Appl. Phys. Vol. 32 (1993) pp. 290-293, Part 1, No 1B, January 1993

EXAMINER Joseph Williams DATE CONSIDERED 1/8/05

*EXAMINER: *Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.*